# Monthly LabAdviser update: 7/4 2017

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| Updated Subject | Contributor | Link to the updated pages |
| **TPT – courses**  The Danchip Tool Package Training courses are described here. In the future these will be the entry courses to getting tool trainings at Danchip. | **Thomas, Pernille**  **Jonas and Berit @danchip** | [Courses](http://labadviser.danchip.dtu.dk/index.php/LabAdviser/Courses) |
| **PEALD (ALD2)**  ALD of TiN  ALD of AlN  ALD of SiO2  ALD of HfO2  ALD of TiO2  Al2O3 of Al2O3 | **Tanja Amport @danchip** | [TiN\_deposition\_using\_ALD2](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD2_(PEALD)/TiN_deposition_using_ALD2)  [AlN\_deposition\_using\_ALD2](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD2_(PEALD)/AlN_deposition_using_ALD2)  [SiO2\_deposition\_using\_ALD2](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD2_(PEALD)/SiO2_deposition_using_ALD2)  [HfO2\_deposition\_using\_ALD2](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD2_(PEALD)/HfO2_deposition_using_ALD2)  [TiO2\_deposition\_using\_ALD2](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD2_(PEALD)/TiO2_deposition_using_ALD2)  [Al2O3\_deposition\_using\_ALD2](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD2_(PEALD)/Al2O3_deposition_using_ALD2) |
| **ALD1**  ALD of ZnO and AZO deposition | **Evgeniy Shkondin @fotonik** | [Thin\_film\_deposition/Deposition\_of\_ZnO](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_ZnO)  [ALD\_Picosun\_R200/ZnO\_deposition\_using\_ALD](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD_Picosun_R200/ZnO_deposition_using_ALD)  [Thin\_film\_deposition/Deposition\_of\_AZO](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_AZO)  [ALD\_Picosun\_R200/AZO\_deposition\_using\_ALD](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD_Picosun_R200/AZO_deposition_using_ALD) |
| **Technology research**  The Ph.d. project “Fabrication of Hyperbolic Metamaterials using Atomic Layer Deposition” has been ended and is presented here. | **Evgeniy Shkondin @fotonik** | [Technology\_Research/Fabrication\_of\_Hyperbolic\_Metamaterials\_using\_Atomic\_Layer\_Deposition](http://labadviser.danchip.dtu.dk/index.php/LabAdviser/Technology_Research/Fabrication_of_Hyperbolic_Metamaterials_using_Atomic_Layer_Deposition) |
| **PECVD4**  Some PECVD4 results added to relent process pages | **Berit Herstrøm @danchip** | [Deposition\_of\_Silicon\_Oxide\_using\_PECVD](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_Silicon_Oxide/Deposition_of_Silicon_Oxide_using_PECVD)  [Deposition\_of\_Silicon\_Nitride\_using\_PECVD](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_Silicon_Nitride/Deposition_of_Silicon_Nitride_using_PECVD) |
| **Spin Coaters**  This page has been updated | **Thomas A. Anhøj @danchip** | [Lithography/Coaters](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/Coaters) |
| **SIMS**  Our SIMS has been decommissioned. We have added a link to a SIMS service provider. | **Jesper Hanberg @danchip** | [Characterization/Element\_analysis](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/Element_analysis) |
| **New equipment in pipeline**  This page has been updated | **Berit Herstrøm @danchip** | [New\_equipment\_in\_the\_pipeline](http://labadviser.danchip.dtu.dk/index.php/LabAdviser/New_equipment_in_the_pipeline_and_Old_equipment_for_decommissioning) |

# Equipment Manuals updated in LabManager:

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

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|  | **Manual for Aligner\_6inch\_ EVG620.** |
|  | **Manual for Plasma Asher1\_Model 300 Plasma Processor** |
|  | **Manual for KS Aligner\_ MA6** |
|  | **Manual for SU-8 Developer Bench** |
|  | **Manual for Inclined UV-lamp** |
|  | **Manual for Oven 110-250C** |
|  | **Manual for Oven 90C** |
|  | **Manual for Aligner: Maskless 01** |
|  | **Manual for Spin coater: Labspin 02** |
|  | **Manual for Spin coater: Labspin 03** |
|  | **Manual for Sputter Coater 03** |
|  | **Manual for Aluminium etch** |
|  | **Packlab: Plasma Asher Pico 2** |